

Semiconductor and High Technology



Equipment Solutions



The Company

SisteM Technology is a full service company in operation since June 2004. Prior to this, SiSTEM's founder, Chris Ridge, had worked in the semiconductor and high technology industries for over 30 years in research and development, process engineering and later capital equipment distribution.

Our Goals

Our company goals are to supply to our customer's advanced technology products which meet their needs of quality build and reliability, on-time delivery, and competitive cost. Only in this way will we establish a justifiable reputation as a key supplier in what is an increasingly demanding and ever-changing advanced technology market place.

Our Suppliers

A key part of our success to date may be attributed to the impressive list of manufacturing suppliers that we are privileged to represent in the UK and Ireland, Europe and, in some cases ,Globally. Many of these companies are world-wide leaders in their fields and they continue to contribute to the outstanding developments and ranges of products offered by the Micro and Nano-electronics, Photovoltaic, Thin Film display, and other High Technology industries.

Customer Support

From our offices in the Caswell Science & Technology Park, we support our customers across the UK and Ireland and in Mainland Europe. We offer installation, commissioning, warranty support, service contracts and upgrades from our factory-trained engineers who share our commitment to quality of supply.

Marketing and Affiliations

SiSTEM Technology has attended at many of the UK and Ireland exhibitions and conferences in recent years and our customer base continues to grow as a result of our ever –increasing exposure through these events. Our affiliations with the UK's leading trade associations for our industry, NMI (National Microelectronics Institute) and JEMI (Joint Equipment and Materials Initiative) also play a major role in helping to promote the goods and services our company provides.











Atomic layer Deposition





PICOSUN R-SERIES

Manual or semi-automatic processing for research and development

PICOPLASMA™ Source System

Picosun's innovative PICOPLASMA [™] plasma enhanced ALD (PEALD) source system is based on a highly advanced, ionfree remote plasma source.

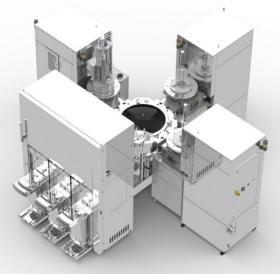




PICOSUN P-SERIES

Fully automatic single wafer, cluster and batch processes for high-volume manufacturing





Atomic layer Deposition





PICOSUN[™] novel, innovative Roll-to-Roll ALD Coating System.

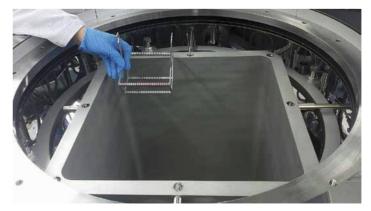
ALD is well suited technique for depositing thin inorganic coatings onto temperature-sensitive and/or flexible

Picofloat[™] Particle Coating System

The powder to be coated is in a constant motion which ensures uniform ALD film formation on every particle down to nano-scaled dimensions

PICOSUN[™] P-1000 ALD Reactor

Has an extra-large reaction chamber for wafers up to 450 mm diameter, sheets of glass, and large batches of 3D objects.



Sputtering Systems



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MRC 603 Fully Refurbished



MRC 943 Fully Refurbished



New Confocal Sputtering Systems



New R & D Sputtering Systems



MRC ECLIPSE Fully Refurbished / Re-manufactured Sputtering Systems

Guaranteed to meet or exceed OEM Specifications

Photolithography

Spin Coat, Develop, Etch and Bake Systems



Supplies that meet your time, cost and quality expectations.

solarsemi

Wet Process



Wet processing stations and ancillaries for batch or single wafer substrates and wafers.

From simple manual though semi-automated to fully automated C2C systems.

International Standards - SEMI-S2, UL, CE.

Materials of construction; PP, FRPP, PVDF, CPVC and Stainless Steel

Chemical Delivery Systems

Bulk Chemical Dispense Systems, , Portable Chemical Handling Equipment, Chemical Dosing, Feed and Bleed



Simple PP acid etch bench

Semi-Auto Rotary Robot

etch bench



SS Solvent wet bench



Fully-Automated Linear Robotic wet bench

Chemical Heaters





Teflon In-line heater

Teflon Immersion heater

SH Gas/Solvent heater



Ultra-Pure DI water heater



HOTSHOT Quartz chemical Heater



High Temp Filter Housing



Megasonics



Megasonic Tank Systems. Stainless Steel, Quartz or Kynar tanks with Direct mounted transducer arrays

MegPie Single Wafer Radial

Megasonic transducer

Thermal Process



RCH ASSOCIATES, INC

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Horizontal Diffusion Furnaces

RCH Associates specializes in new LPCVD/Diffusion systems as well as replacement OEM gas systems (Thermco, Bruce, Tempress, ACS, etc.) fully retrofittable into existing or remanufactured source cabinets.

RCH's portfolio of products and capabilities extends from basic Bench Top Furnaces or Research Grade systems to high production, full capability horizontal stacks

The ASTRA CONTROL SYS-TEM provides Ethernetlinked, integrated controls with touch screen graphical simplicity.







Furnace Elements and Insulation Products

Electric Furnace Systems which operate in Air or Inert Gas to 3000 F.

- Heating Chambers for :
- Wafer Processing Furnaces, Muffle Furnaces and Industrial Processing
- Ceramic Vacuum Formed Fibrous Components including:
- Heating Elements and Custom Shapes
- High Temperature Gaskets & Seals for door jams, pillows etc.
- Vestibule Blocks
- Foundry Service: We offer a complete line of heating and insulation products





DS Fibertech Corporation Leaders in applied heat technology

Torch Element

Vertical Furnace Element

Replacement Furnace Elements for TEL, ASM, SVG THERMCO, KOKUSAI, TEMPRESS and Others

Thermal Process

Vacuum and Convection Ovens



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Fortrend-YES have partnered to develop the SIO-300-450 series of High Temperature, Air Cooled, Controlled Process Gas Composition, Laminar Cross Flow, Vertical Vacuum Ovens the result of many years experience in the design of low particle and Oxygen Concentration systems.



The SIO-450-250 system incorporates the 450mm version of a state-of-the-art thermal curing chamber developed by Fortrend. The SIO-450-250 is offered for either vertical or horizontal wafer orientation to meet the process requirements. The system can have either one curing chamber with two FOUP's or two chambers with Four FOUP's to double the through put at lower cost.

450mm Automated High Performance Thermal Curing System, SIO-450-250

Probe and Test

Cantilever Probe Cards

Epoxy: Mainstream Applications and fine pitch down to 44 µm. Multi-die Testing. Fine pitch Shelf cards.

Blade: Hybrid devices testing, special applications.

Parametric Technology: Parametric testing, low leakage and ultra low leakage down to 1 FemtoAmp/Volt for Keithley/ Agilent and others.

Probe Cleaning Materials

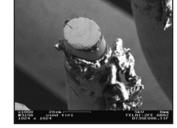
Probe Clean

Probe Polish

Probe Scrub

Probe Lap

Probe Form



From flat contaminated tips

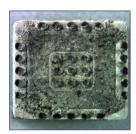


Cleaned and re-shaped tips

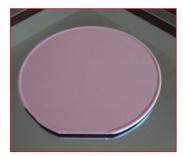
То

Test Socket Cleaning Materials

"On-Line" Test Socket Cleaning for **Increased Yield with Reduced Rescreen**



Chuck Cleaning Wafer Engineered Cleaning Solutions for Wafer Handling



Compliant Edge Ring Wafer Handler Arm



Tools and Wafer Chuck

Compliant Surface Eject Features for ESC Chuck









Vacuum Traps

MV Multi-Trap[®]

High Capacity, High Efficiency, Vacuum Inlet Trap Removes corrosive and abrasive particles that can destroy your vacuum pump Extends Pumping System Preventative Maintenance periods by up to 2 times or more.

Common Applications are; LPCVD, PECVD, METAL ETCH, MOCVD, ION IMPLANT, HVPE,





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MV Posi-Trap[®]

Foreline Trap Ensures positive flow with no "blow-by" All stainless steel construction Straight-thru and right-angle styles offered Wide variety of filter elements to choose from

Midi-Mist[™] & Maxi-Mist[™]

Stainless steel construction resists corrosion Protects environment from vacuum pump exhaust Drain plug for recovering pump fluids Simple disassembly and cleaning High-capacity coalescing filters drain oil into a large reservoir for easy recovery Designed for large capacity vacuum pumps





VisiTrap®

Vacuum Inlet trap with transparent Sump

Select inserts for trapping particles, water, oil, or corrosive chemicals

Transparent sump shows when to change insert without removing from vacuum system



Visi®Flow

A compact, portable, self-contained system for continuously filtering mechanical vacuum pump fluid



Handling and Automation



Mass Wafer Transfer Systems .



Fortrend PLM-200 EUV

SMIF Pod Opener





450mm FOUP Opener, FO-4500



PLM-C1[™], Pod Lift Mechanism



Four cassette transfer robot types -> flexible combinations

Fortrend PIS 200 EUV Dual Pod Opener & Inner Box



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FORTREND

Handling and Automation

Reticle Storage Systems



Lamina-203 – Three load port configuration

LED Sorters and EFEMs

50mm – 200mm Open Cassette Wafers The LED Sorter is based on Fortrend's successful200 and 300mm wafer sorters used in the Semi-conductor FABS.



Fortrend's eRack system



InforTrac[®] Hardware Solutions for Lot ID Tracking System

Three Protocols are available for all InforTrac[®] RFID Reader/Writer (4) SEMI SECS-II (5) ASYST TAG Messages (6) Custom messages



Reader RFT-2000x-LCD

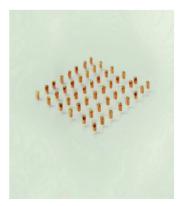




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Evaporation Materials





Cu evaporation materialNi starter source materialSupplies that meet your time, cost and quality expectations.

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Photovoltaics

Automated PV Cell Load/Unload Transfer System for Tray



TLS6030

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FORTREND

For tray type PV carriers. This improved version offers back side contact only and PV cell transfers at the lowest cost of ownership to OEM customers. It is also equipped with advanced features like Fortrend proprietary on-the-fly cell breakage inspection system, broken cell recovery robot, empty cassette buffers, tray preheat cycles and manual tray load/unload port, and flexible tool interfaces for PECVD and RIE tool makers.

Automated PV Cell Load/Unload Transfer System for Ion Implantation System RCT- 0602

Ion implantation is a technique that has been demonstrated to improve solar cell efficiency and eliminate process steps in standard and advanced cell designs. Fortrend has developed a high efficiency PV cell load/unload transfer system, RCT-0602, for PV ion implanters. This system transfers 6 cells in a batch to vacuum chamber from a single cassette and returns the cells back automatically. It is also equipped with advanced features like Fortrend proprietary on-the-fly cell breakage inspection system, broken cell recovery robot, and SCARA robot for transferring cells in and out of vacuum chamber.







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